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Bib Data Sheet

CONFIRMATION NO. 5143

SERIAL NUMBER 09/597,161	FILING DATE 06/20/2000 RULE	CLASS 257	GROUP ART UNIT 2815	ATTORNEY DOCKET NO. 025311/0105	
APPLICANTS Ichiro Okabe, Kanagawa, JAPAN; Hiroki Arai, Tokyo, JAPAN;					
** CONTINUING DATA *****					
** FOREIGN APPLICATIONS ***** JAPAN HEI 11-174761 06/21/1999					
IF REQUIRED, FOREIGN FILING LICENSE GRANTED ** 08/09/2000					
Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 (a-d) conditions <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after met Allowances Verified and Acknowledged Examiner's Signature _____ Initials _____		STATE OR COUNTRY JAPAN	SHEETS DRAWING 3	TOTAL CLAIMS 5	INDEPENDENT CLAIMS 3
ADDRESS Foley & Lardner 3000 K Street NW Washington, DC 20007-8696					
TITLE Method of forming a fine pattern using a silicon-oxide-based film, semiconductor device with a silicon-oxide-based film and method of manufacture thereof					
FILING FEE RECEIVED 690	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:		<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time) <input type="checkbox"/> 1.18 Fees (Issue) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit		